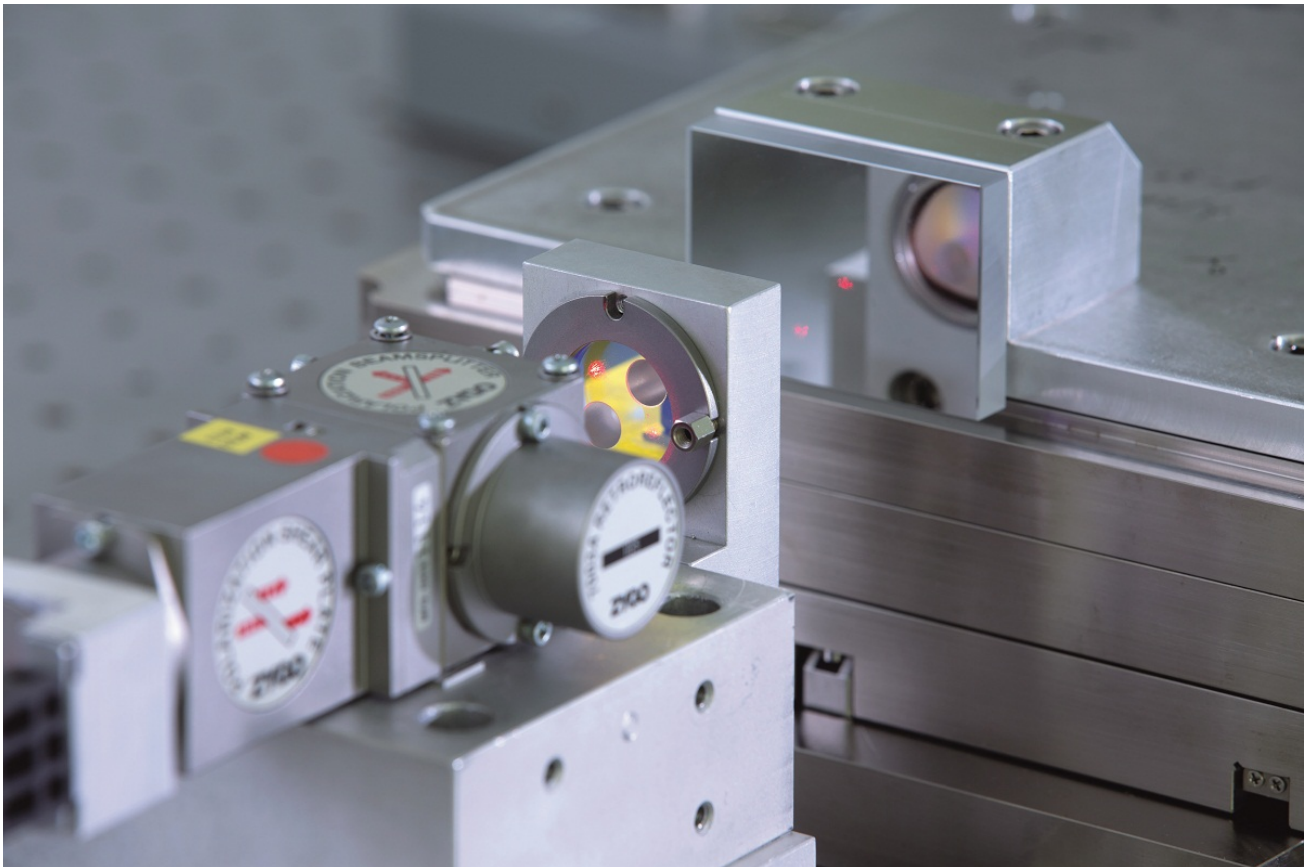


## Metrology Equipment Overview

Measuring Environment / Measuring Equipment Portfolio



## Measuring Equipment According to Measurand

Length / Path			
Measuring equipment	Measuring principle	Resolution/DPMI	Measuring range
Tactile measuring sensor	Inductive (incremental)	to 5 nm	to 50 mm
Laser interferometer	Optical (incremental)	to 0.151 nm	to 10 m
Vibrometer	Optical (Doppler effect)	2 nm	40 mm
Multi-sensor measuring machine	Optical and tactile	0.1 $\mu\text{m}$	300 mm $\times$ 300 mm $\times$ 160 mm
CNC coordinate measuring machine	Incremental sensor with glass scale	0.1 $\mu\text{m}$	900 mm $\times$ 1800 mm $\times$ 800 mm
PISeca	Capacitive sensor	0.001 % of the travel range	to 100 $\mu\text{m}$

Angle			
Measuring equipment	Measuring principle	Resolution/DPMI	Measuring range
Laser interferometer	Optical (incremental)	to 34 nrad	$\pm 0.11^\circ$
Autocollimator (AKF)	Optical (autocollimation)	to 0.05 arcsec	$\pm 0.29^\circ$ (up to $\pm 2.3^\circ$ )
Angle measuring device / rotary encoder	Incremental	to 0.4 arcsec	360°

Velocity			
Measuring equipment	Measuring principle	Velocity resolution	$V_{\text{max}}$
Laser interferometer	Optical (incremental)	to 10 nm/s	up to 4 mm/s
Vibrometer	Optical (Doppler effect)	to 0.005 $\mu\text{m/s}$	up to 10 mm/s

Surface finish / surface flatness			
Measuring equipment	Measuring principle	Resolution/DPMI	Measuring range
White light interferometer	Optical (incremental)	$\lambda/25$	80 mm $\times$ 80 mm
White light interferometer	Optical (scanning white light interferometry)	to 1 nm for smooth surfaces	Z=70 mm X=38 mm Y=28 mm
Laser scanning microscope	Optical		X=100 mm; Y=100 mm; 1 $\times$ - 8 $\times$ objective

Eccentricity / wobble			
Measuring equipment	Measuring principle	Resolution/DPMI	Measuring range
Static spindle analyzer	Capacitive	80 $\mu\text{V}/\mu\text{m}$	Low $\pm 125 \mu\text{m}$ High $\pm 6.5 \mu\text{m}$